

1765

In re PATENT

F0632

CERTIFICATE OF MAILING

I hereby certify that this correspondence (along with any paper referred to as being attached or enclosed) is being deposited with the United States Postal Service on the date shown below with sufficient postage as first-class mail in an envelope addressed to: Mail Stop Non-Fee Amendment, Commissioner for Patents, P.O. Box 1450, Alexandria, Virginia 22313-1450.

Date: 12/23/03

Rebecca A. Bellas

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re patent application of:

Applicant: Phan, et al.

Examiner: Duy Vu Nguyen Deo

Serial No: 10/052,173

Art Unit: 1765

Filing Date: January 17, 2002

Title: IN-SITU CHEMICAL COMPOSITION MONITOR ON WAFER DURING PLASMA ETCHING FOR DEFECT CONTROL

**Mail Stop Non Fee Amendments
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450**

REPLY TO OFFICE ACTION DATED SEPTEMBER 25, 2003

Dear Sir:

Favorable reconsideration of the above-identified patent application is respectfully requested in view of the amendments and comments below.

Claims 5-8, 20, and 21 have been amended on pages 3 and 4.

Replacement sheets for all figures (1-6) are attached.